



#1767

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Yong-Pil Han et al.

Group Art Unit: 1763

Serial No.: 09/498,303

Examiner: T. Dang

Filed: February 4, 2000

For: HF VAPOR PHASE WAFER CLEANING AND OXIDE ETCHING

THE ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, DC 20231

I hereby certify under 37 CFR 1.8(a)  
that this correspondence is being  
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**GROUP 1700**

*Theresa A. Lober*  
July 12, 2002

**PETITION FOR ONE-MONTH EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)**

Hereby is petitioned the Assistant Commissioner for Patents to extend for the patent application referenced above the period for response to the Examiner's Action mailed March 13, 2001, for ONE (1) month, extending the last day of the response period from June 13, 2002, up to and including July 15, 2002. A response to the Examiner's Action is being filed on even date herewith.

Please apply the \$200.00 fee under 1.17(a)(2) to Deposit Account No. 19-2553. Please apply any deficiency in the stated fee, any other required fees, and please apply any overpayment, to Deposit Account No. 19-2553.

07/10/2002 HBERHE 00000002 192553 09498303  
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Respectfully submitted,

Date

*July 12, 2002*

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